## Recombination dynamics in pseudomorphic and partially relaxed In<sub>0.23</sub>Ga<sub>0.77</sub>As/GaAs quantum wells

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A systematic investigation of the recombination dynamics of excess charge carriers in  $In_{0.23}Ga_{0.77}As/GaAs$  single quantum wells as a function of well width covering the range from the pseudomorphic to the partially relaxed regime reveals for the first time the impact of misfit dislocations on carrier decay times. At dislocation densities  $n_L = 5 \times 10^5 \text{ m}^{-1}$  the recombination changes its character from predominantly radiative (excitonic) to nonradiative. A diffusion model describes quantitatively the observations and full agreement is obtained with independent determination of the quantum efficiency. Excitonic,  $(e, A^0)$ , and  $(D^0, A^0)$  recombination times are determined. The intrinsic ambipolar diffusion length is observed to be 0.5  $\mu$ m, indicating a huge hole mobility of 1400 cm<sup>2</sup>/V s at 10 K. Time-resolved cathodoluminescence provides the experimental results.

The  $Al_x Ga_{1-x} As/GaAs$  material system has played a key role in the development of semiconductor heteroepitaxy because it is nearly lattice matched for all x. Fundamental breakthroughs in two areas were achieved with this system.

(1) A large number of novel electronic and photonic heterostructure devices has been designed with performance superior to homoepitaxial devices.<sup>1,2</sup>

(2) A basic understanding of heteroepitaxial growth processes and the physics of quantum wells has been obtained.<sup>3,4</sup>

Presently  $In_xGa_{1-x}As/GaAs$  plays a role similar to that of a model system for the heteroepitaxy of latticemismatched materials. By means of this system the performance of a variety of devices can be dramatically improved<sup>5-7</sup> and we learn about the basic mechanisms ruling the growth of lattice-mismatched layers<sup>8,9</sup> and the physics of strain relaxation.<sup>10-12</sup> Actual device structures include layers with thickness in the pseudomorphic regime as well as layers exceeding the critical thickness.

In particular for lattice-matched  $Al_xGa_{1-x}As/GaAs$ (Refs. 13 and 14) and to a lesser extent for In<sub>0.53</sub>Ga<sub>0.47</sub>As/InP (Refs. 15 and 16) quantum wells (QW's) the recombination dynamics has been carefully investigated; the excitonic lifetime shows a strong increase upon increasing QW width  $L_z$  due to decreased overlap wave function. of the excitonic For the  $In_xGa_{1-x}As/GaAs$  system, to our knowledge, no reports on this subject exist although the recombination dynamics is of essential importance for the understanding of optical device performance. Only the dynamics of carrier capture into  $In_xGa_{1-x}As/GaAs$  QW's has been investigated in Ref. 17. In this paper we present the first investigation of recombination dynamics in *pseudomorphic* and *partially relaxed* QW's. Low-temperature recombination lifetimes for  $In_xGa_{1-x}As/GaAs$  single QW's are reported and the large influence of misfit dislocations on the recombination dynamics is assessed. With increasing dislocation density the character of the recombination is observed to change from purely radiative to increasingly nonradiative.

Our samples are grown by molecular-beam epitaxy (MBE) and consist of a semi-insulating GaAs substrate, a 1500-Å undoped GaAs buffer layer, a single QW of  $In_xGa_{1-x}As$  (x = 0.23) with thickness  $L_z$  [ $L_z = 16,22,27,32,38$  nm for samples No. 1 (B1309), No. 2 (B1310), No. 3 (B1311), No. 4 (B1312), and No. 5 (B1313), respectively], and a 50-nm cap layer of GaAs. The growth temperature of the  $In_xGa_{1-x}As$  layer was 515 °C. Further details on the growth procedure can be found elsewhere.<sup>18,19</sup>

In our time-resolved cathodoluminescence (CL) experiment the sample is excited by 50-ns electron pulses, long enough so that a quasiequilibrium of the carriers is reached. The electron beam is switched off with a decay time of less than 200 ps (Ref. 20) and the luminescence decay is measured by means of a temperature-stabilized and Peltier-cooled Si avalanche photodiode (RCA C30902S,  $\lambda \leq 1100$  nm) and time-correlated single-photon counting. The time resolution of the whole setup is 350 ps. The acceleration voltage is U = 30 kV and a typical beam current is 1 nA. At low dislocation densities  $(n_L \le 10^5 \text{ m}^{-1})$  the transients are measured with the electron beam focused between single dislocations (spot mode). In samples with higher  $n_L$  the excitation volume of about 4  $\mu$ m (Ref. 21) averages over clusters of dark line defects and brighter areas in between.

In Fig. 1 we compare transients of samples No. 1, No.

41 10 120

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FIG. 1. CL transients at low temperature for samples with different dislocation density  $n_L$ . Increasing  $n_L$  leads to faster decay.

3, and No. 5 with  $L_z = 16$ , 27, and 38 nm, respectively, at T = 6 K. The results for samples No. 2 and No. 4, with  $L_z = 22$  and 32 nm are not shown, for clarity. It is evident that with increasing  $L_z$ , i.e., with increasing dislocation density  $n_L$ , the decay becomes much faster. The transients can be almost perfectly fitted by a sum of two exponentials with time constants  $\tau_1$  and  $\tau_2$ , which are plotted in Fig. 2(c) versus  $L_z$ . The misfit dislocations generated at the heterointerface when the layer thickness exceeds the critical thickness are centers of *locally* reduced quantum efficiency and *locally* reduced excess charge carrier lifetime.<sup>19</sup> With increasing dislocation density the *local* reduction of quantum efficiency  $\eta$ . A diffusion model<sup>19</sup> gives the theoretical dependence

$$\eta = 1 - 2Ln_L \tanh[1/(2Ln_L)], \qquad (1)$$

L being the ambipolar diffusion length. The measured misfit dislocation density  $n_L$  is plotted in Fig. 2(a) as a function of  $L_z$ . In Fig. 2(b) the experimental total quantum efficiency and its prediction according to Eq. (1) and a diffusion length  $L = 0.5 \,\mu m$  are compared and found to agree perfectly. The decrease of quantum efficiency with increasing  $L_z$  predominates the  $L_z$  dependence of the transients at larger well widths. The high quantum efficiency on the 16- and 22-nm QW's makes it straightforward to identify the decay constant  $\tau_1$  with the radiative excitonic [X(e,hh), n = 1] lifetime  $\tau_r$ . The excitonic lifetime in the thicker well is slightly larger, as expected from the theory of excitonic oscillator strength in QW's.<sup>22</sup> The values of about 2 ns compare well to values found for lattice-matched systems like Al<sub>x</sub>Ga<sub>1-x</sub>As/ GaAs (Refs. 13 and 14) and  $In_{0.53}Ga_{0.47}As/InP$  (Ref. 16) at low temperatures and provide further evidence for the high quality of our samples in addition to the large diffusion length. The time constant  $\tau_2$  is given by  $(e, A^0)$ recombination as will be discussed below. Figure 2(c) shows that for thicker wells  $(L_z \ge 27 \text{ nm})$  the decay constants decrease strongly due to the increasing importance



FIG. 2. (a) Line misfit dislocation density  $n_L$ , (b) quantum efficiency  $\eta$  (solid line is theoretical curve from simple diffusion model) and (c) decay constants of CL transients, solid line denotes theoretical description by diffusion model, dashed line is guide to the eye.

of dislocations for the dynamics of the recombination. To evaluate their influence in more detail now we use our simple diffusion model treating the dislocation lines at an average distance  $d = 1/n_L$  as fast nonradiative recombination centers.<sup>19</sup> The rate equation including diffusion for an excess charge carrier density *n* is

$$\frac{\partial n(x,t)}{\partial t} = -\frac{n(x,t)}{\tau_{\text{tot}}} + D \frac{\partial^2 n(x,t)}{\partial x^2} , \qquad (2)$$

*D* being the diffusion coefficient and  $\tau_{tot}$  the total recombination lifetime given by the radiative lifetime  $\tau_r$  at high quantum efficiency. With  $\tau_r = 2$  ns and  $L = 0.5 \,\mu\text{m}$  determined above, an ambipolar diffusion coefficient  $D = L^2/\tau_r = 1.2 \text{ cm}^2/\text{s}$  is obtained. The ambipolar mobility which is dominated by the hole mobility at T = 10 K is  $\mu = De / kT = 1.4 \times 10^3 \text{ cm}^2/\text{V}$  s, a surprisingly high value.

The recombination dynamics is well described by an approximate solution of Eq. (2) found by development into a Fourier series and taking only the leading term

GRUNDMANN, BIMBERG, FISCHER-COLBRIE, AND MILLER

into account. The actually observed decay time  $\tau$  is then given by

$$\frac{1}{\tau} = \frac{1}{\tau_r} + \frac{1}{\tau_D} = \frac{1}{\tau_r} [1 + (\pi L n_L)^2] .$$
(3)

 $\tau_D = 1 / [D (\pi n_L)^2]$  is a lifetime caused by the presence of misfit dislocations. Thus for low dislocation density  $(Ln_L \ll 1)$  the decay time is given by the radiative excitonic lifetime. At high dislocation densities  $(Ln_L \gg 1)$ the recombination dynamics is dominated by  $\tau_D$  describing the diffusion into dislocations and fast nonradiative decay there. It is expected from Eq. (3) that  $\tau_D$  is equal to  $\tau_r$  (i.e., 50% quantum efficiency) for  $n_L = 6.4 \times 10^5$  m<sup>-1</sup>. The 27-nm QW, which is the thinnest QW showing a drop of lifetime, has exactly 50% quantum efficiency, and the experimentally observed dislocation density is  $n_L = 5.1 \times 10^5 \text{ m}^{-1}$  in very good agreement with the prediction above. The dislocations in the QW's thinner than 27 nm are not expected to deteriorate the lifetime in agreement with experiment. The theoretical  $L_z$  dependence of the dominating recombination time constant  $\tau_1$ including the variation of excitonic oscillator strength and the influence of the misfit dislocations is shown in Fig. 2(c) as a solid line. The decay time changes its character from radiative  $(n_L \le 10^5 \text{ m}^{-1})$  to increasingly nonradiative  $(n_L \ge 10^6 \text{ m}^{-1})$ .

Using long signal integration times and taking advantage of the high dynamics of single photon counting, we found that the transients of the almost unrelaxed QW's with  $L_z = 16$  and 22 nm exhibit a third nonexponential decay. As an example the transient of the 22-nm QW is shown in Fig. 3 on a much larger time scale than that of Fig. 1. This decay is governed by the  $(D^0, A^0)$  recombination. The best possible fit with a single exponential is shown in Fig. 3 to be clearly unsatisfactory. The assignment of  $\tau_2$  to the  $(e, A^0)$  and the third decay to the  $(D^0, A^0)$  process are based upon a detailed discussion of the time-delayed spectra presented below.

Observation of the thermalization of the excess carriers



FIG. 3. CL transient of  $L_z = 16$  nm QW on larger time scale showing a long decay time  $\tau_3$  attributed to extrinsic  $(D^0, A^0)$ recombination. Solid line is  $\chi^2$  fit.

measured by means of time-delayed CL spectra gives further insight into the recombination dynamics. Experimentally several time windows are set into the transient at different delay times  $\Delta t$  with respect to the end of the electron pulse and spectra are taken for all these windows simultaneously. In Fig. 4 the time evolution of the spectrum of the  $L_z = 16$  nm QW is shown. The evolution includes several steps.

(1) Carriers relax from higher subbands.

(2) The spectral maximum of the X(e,hh), n = 1 transition shifts slightly to lower energies indicating the thermalization of carriers within the inhomogeneous spectral broadening.

(3) At delay times longer than 4 ns the  $(e, A^0)$  transition completely dominates the spectrum. Since the material is, however, p type in character, free electrons are captured by both free and bound holes and ionized donors.

(4) Finally the  $(D^0, A^0)$  recombination remains causing the clearly nonexponential decay as visualized in Fig. 3.

This behavior is rather three dimensional in character, similar to what has been reported by Christen *et al.*<sup>13</sup> for an 11-nm Al<sub>x</sub>Ga<sub>1-x</sub>As/GaAs multiple QW. The peak assignments and the peak positions denoted by arrows in Fig. 4 stem from photoluminescence and absorption investigations.<sup>23</sup> The acceptor binding energy  $E_b^A$  in the QW is 15 meV, which agrees well with the theoretical value of 16 meV.<sup>24</sup> The capture cross section  $\sigma(e, A^0) = (\tau_2 v_{th} p)^{-1}$  of free electrons onto neutral acceptors can be calculated from the  $(e, A^0)$  recombination



FIG. 4. Time-delayed spectra (scaled to same height) of 16nm QW, showing thermalization of carriers. At long delay time  $\Delta t$  the  $(D^0, A^0)$  recombination dominates the spectrum. The inset displays schematically the excitation pulse.

time constant  $\tau_2 = 5.4 \pm 0.2$  ns and the experimentally determined background (*p*-type) impurity concentration  $p = 5 \times 10^{14}$  cm<sup>-3</sup>.  $v_{\rm th} = (2kT/m_e)^{0.5}$  is the thermal electron velocity; assuming a mean electron temperature of 10 K and  $m_e = 0.055m_0$  we obtain  $v_{\rm th} = 7.4 \times 10^6$  cm/s. Then the capture cross section is  $\sigma(e, A^0) = 5 \times 10^{-14}$  cm<sup>2</sup>.

In summary we have presented a systematic investigation of recombination dynamics in partially relaxed  $In_{0.23}Ga_{0.77}As/GaAs$  QW's. The character of recombination changes from radiative to nonradiative upon increase of misfit dislocation density. The threshold is at  $L_z$  values appreciably larger than the transition from pseudomorphic to partially relaxed QW's. The thermalization of carriers has been visualized by time-delayed spectra.

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